L Number	Hits	Search Text	DB	Time stamp
-	35666	mems or mem or microelectromechanical or	USPAT;	2004/09/01 11:54
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)		
•	235	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 11:54
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2		
		factor\$1)		
	204	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 11:55
-		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	200 1/00/01 11:00
i		or (micro near2 mechanical) or microelectrical or	00.00	
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2		
		factor\$1)) and (mirror\$1 reflect\$3)		
	150	(((mems or mem or microelectromechanical or	LICDAT	2004/00/04 44:55
	130		USPAT;	2004/09/01 11:55
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2		
		factor\$1)) and (mirror\$1 reflect\$3)) and wavelength\$1		
-	81	((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 11:57
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2		
		factor\$1)) and (mirror\$1 reflect\$3)) and wavelength\$1) and		
		((pivot\$3 tilt\$3 rotat\$3 actuat\$3) with (mirror\$1	1	
•		micromirror\$1 (micro near2 mirror\$1)))		
_	37	(((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:07
	•	micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	200 1/00/07 12:07
		or (micro near2 mechanical) or microelectrical or	001 01 05	
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2		
		factor\$1)) and (mirror\$1 reflect\$3)) and wavelength\$1) and		
		((pivot\$3 tilt\$3 rotat\$3 actuat\$3) with (mirror\$1		
ĺ	70	micromirror\$1 (micro near2 mirror\$1)))) and multiplex\$3	LICEAT	0004/00/04 40:40
-	73	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:10
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (high adj2 fill		
		adj2 factor)		-
-	22	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:08
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		İ
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (high adj2 fill		
		adj2 factor)) and multiplex\$3		
_	20	(((mems or mem or microelectromechanical or	USPAT:	2004/09/01 12:09
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	200 1/00/01 12:00
		or (micro near2 mechanical) or microelectrical or	33   3, 0,	1
		microelectricalmechanical or (micro near2 electrical) or		
j				
		(micro near2 electrical near2 mechanical)) and (high adj2 fill		
		adj2 factor)) and multiplex\$3) and mirror\$1		0004/05/57
-	41	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:10
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and ((high adj2 fill		1
		adj2 factor) same (mirror\$1 reflect\$3))	1	

	<del>,</del>			
-	9	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical)	USPAT; US-PGPUB	2004/09/01 12:19
		or (micro near2 mechanical) or microelectrical or	03-PGPUB	
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and ((high adj2 fill		
		adj2 factor) same (mirror\$1 reflect\$3))) and multiplex\$3		
-	44631	mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:34
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
į		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
İ		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)	IBM_TDB	
-	232	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:19
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)		
-	200	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:20
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
1		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (reflect\$3 mirror\$1)	_	
-	35188	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:21
1		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
	1	factor)) and (reflect\$3 mirror\$1)) ((monolith\$3 (single near2		
	1	crystal)) near4 substrate\$1)		
-	14	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:21
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (reflect\$3 mirror\$1)) and ((monolith\$3 (single		
	10	near2 crystal)) near4 substrate\$1)	LICDAT	0004/00/04 40:40
-	10	((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:46
1		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (reflect\$3 mirror\$1)) and ((monolith\$3 (single	IBM_TDB	
	1	near2 crystal)) near4 substrate\$1)) and (multiplex\$3		
	1	wavelengths)		
-	2	6137941.pn.	USPAT;	2004/09/01 14:05
]			US-PGPUB;	230-703/01 14.00
1	1		EPO; JPO;	
1	1		DERWENT:	
1	1		IBM_TDB	
-	9290	mirror\$1 near4 array	USPAT;	2004/09/01 14:05
	1	,	US-PGPUB	
	1		EPO; JPO;	
	1		DERWENT;	
			IBM_TDB	
-	3043	(mirror\$1 near4 array) and (multiplex\$3 wavelengths)	USPAT;	2004/09/01 14:06
		- , , ,	US-PGPUB;	
			EPO; JPO;	
			DERWENT:	
			IBM_TDB	
-	79	((mirror\$1 near4 array) and (multiplex\$3 wavelengths)) and	USPAT;	2004/09/01 14:06
		(fill adj2 factor)	US-PGPUB;	
1			EPO; JPO;	
			DERWENT;	
			IBM_TDB	

-	4162	(mirror\$1 near4 array) and (multiplex\$3 wavelength\$1)	USPAT; US-PGPUB; EPO; JPO;	2004/09/01 14:06
			DERWENT; IBM_TDB	
-	109	((mirror\$1 near4 array) and (multiplex\$3 wavelength\$1)) and (fill adj2 factor)	USPAT; US-PGPUB;	2004/09/01 14:35
			EPO; JPO; DERWENT;	
-	92	(((mirror\$1 near4 array) and (multiplex\$3 wavelength\$1)) and (fill adj2 factor)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)	IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/09/01 19:00
			DERWENT; IBM_TDB	
-	7	(US-6263123-\$ or US-6760144-\$ or US-6778728-\$).did. or (US-20040130774-\$ or US-20040165243-\$ or US-20030223679-\$ or US-20010026674-\$).did.	USPAT; US-PGPUB	2004/09/01 15:26
-	8	(US-5965886-\$ or US-6778728-\$ or US-6760144-\$ or US-6263123-\$).did. or (US-20040130774-\$ or US-20040165243-\$ or US-20030223679-\$ or	USPAT; US-PGPUB	2004/09/01 15:27
_	7	US-20010026674-\$).did. (US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or	USPAT;	2004/09/01 15:29
		US-6760144-\$).did. or (US-20030223679-\$ or US-20040165243-\$ or US-20040130774-\$).did.	US-PGPUB	200 1/00/01 10:20
-	6	((US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or US-6760144-\$).did. or (US-20030223679-\$ or US-20040165243-\$ or US-20040130774-\$).did.) and	USPAT; US-PGPUB	2004/09/01 15:33
	,	((((mirror\$1 near4 array) and (multiplex\$3 wavelength\$1)) and (fill adj2 factor)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3))		
-	7	((US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or US-6760144-\$).did. or (US-20030223679-\$ or US-20040165243-\$ or US-20040130774-\$).did.) and	USPAT; US-PGPUB	2004/09/01 16:10
-	7	(multiplex\$3 wavelength\$1) (((US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or US-6760144-\$).did. or (US-20030223679-\$ or	USPAT; US-PGPUB;	2004/09/01 16:10
		US-20040165243-\$ or US-20040130774-\$).did.) and (multiplex\$3 wavelength\$1)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)	EPO; JPO; DERWENT; IBM TDB	
-	7	((((US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or US-6760144-\$).did. or (US-20030223679-\$ or US-20040165243-\$ or US-20040130774-\$).did.) and	USPAT; US-PGPUB; EPO; JPO;	2004/09/01 16:10
		(multiplex\$3 wavelength\$1)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)) and (fill adj2 factor)	DERWENT; IBM_TDB	
-	2	6657770.pn.	USPAT; US-PGPUB; EPO; JPO;	2004/09/01 16:09
			DERWENT; IBM_TDB	
-	1	6657770.pn. and (multiplex\$3 wavelength\$1)	USPAT; US-PGPUB	2004/09/01 16:10
-	1	(6657770.pn. and (multiplex\$3 wavelength\$1)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)	USPAT; US-PGPUB; EPO; JPO;	2004/09/01 16:10
		//occ7770	DERWENT; IBM_TDB	
-	0	((6657770.pn. and (multiplex\$3 wavelength\$1)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)) and (fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO;	2004/09/01 16:10
			DERWENT; IBM_TDB	
-	4	(US-6263123-\$ or US-6760144-\$ or US-6778728-\$).did. or (US-20030223679-\$).did.	USPAT; US-PGPUB	2004/09/01 17:55
-	3	((US-6263123-\$ or US-6760144-\$ or US-6778728-\$).did. or (US-20030223679-\$).did.) and (attenuat\$4 block\$3)	USPAT; US-PGPUB	2004/09/01 18:24

. (IUS-26261733-\$ or US-6760144-\$ or US-6776728-\$), did.) and (attenuat54 block\$3) (mems or mem or microelectromechanical or microelectrical or (micro near2 electron ear2 mechanical) or (micro near2 electrical or microelectrical or or (micro near2 electrical or or (micro near2 electrical or or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 e					
Tm   (mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 electrical or microelectrical near) or microelectrical near or microelectrical near or microelectrical near or microelectrical near or microelectrical near or microelectrical near or microelectrical near or microelectrical near or microelectrical near or microelectrical near or microelectrical or microelectrical or or microelectrical near nechanical near or microelectrical near nechanical nechanical	-	3	((US-6263123-\$ or US-6760144-\$ or US-6778728-\$).did. or	USPAT;	2004/09/01 18:24
micromechanical or (micro near2 electrical or microelectricalmechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical) and (high adj2 fill adj2 factor)  - 232 (mems or mem or microelectromechanical or microelectricalmechanical or (micro near2 electrical) or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) and (fill adj2 factor)  - 133 ((mems or mem or microelectromechanical or microenectricalmechanical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or or microenectricalmechanical or (micro near2 mechanical) or (micro near2 mechanical) or (micro near2 mechanical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 mechanical) or (micro near2 mechanical) or (micro near2 electrical) or (micro near2 mechanical) or (micro near2 electrical) or (micro near2 electrica		77			0004/00/04 49:40
or (micro near2 mechanical) or microelectrical or (micro near2 electrical) or (micro near2 electrical near2 mechanical) and (high adj2 fill adj2 factor)  232 (mems or mem or microelectromechanical or micromechanical or (micro near2 electrical) or (micro near2 mechanical) or (micro near2 mechanical) or (micro near2 electrical) or (micro	-	//			2004/09/01 18:42
microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) and (high adj2 fill adj2 factor)  microelectricalmechanical or (micro near2 electrical) or (micro n			·		
(micro near2 electrical near2 mechanical)) and (high adj2 fill Jag2 factor) (mems or mem or microelectromechanical or micromechanical or (micro near2 electrical or microelectricalmechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2) mechanical) or microelectrical or (micro near2) microelectrical or (micro near2 electrical) or (micro near2) mechanical) or microelectrical or (micro near2) electrical or (micro near2) electrical) or (micro near2) electrical) or (micro near2) electrical) or (micro near2) mechanical) or (micro near2) electrical) or (micro near2) mechanical) or (micro near2) electrical or (micro near2) mechanical) or (micro near2) electrical) or (micro near2) mechanical) or (micro near2) electrical or (micro near2) electrical) or (micro near2) electrical) or (micro near2) electrical) or (micro near2) electrical) or (micro near2) electrical) or (micro near2) electrical) or (micro near2) mechanical) or (micro near2) electrical) or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical) or (micro near2) electrical) or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (micro near2) electrical or (mic					
adj2 factor) (mems or mem or microelectromechanical or microenechanical) or (micro near) electrical or microelectrical or microelectrical mechanical) or (micro near) electrical or microelectrical mechanical) or (micro near) electrical or microelectrical near) microelectrical near) microelectrical near) microelectrical or microelectrical or microelectrical or microelectrical or microelectrical or microelectrical or microelectrical or microelectrical or microelectrical mechanical or (micro near) electrical or ERWENT; (micro near) electrical near) microelectrical mechanical or (micro near) electrical or ERWENT; (micro near) electrical or microelectricalmechanical or (micro near) electrical or ERWENT; (micro near) electrical near) microelectrical or microelectricalmechanical or (micro near) electrical or microelectrical mechanical or (micro near) electrical or microelectrical mechanical or (micro near) electrical or microelectrical near) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and (fill sā) pivot\$3 rotat\$3 actuat\$3) (((mems or mem or microelectroenechanical or microelectrical or microelectrical near) microelectrical or microelectrical near) microelectrical or microelectrical near) microelectrical or microelectrical near) and (fill adj2 factor)) and (attenuat\$3 block\$3))					
232				IRW_LDR	
micromechanical or (micro near2 electron near2 mechanical) or (micro near2 mechanical) or microelectrical mechanical) or microelectrical mechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)   133 ((mems or mem or microelectromechanical or micromechanical or (micro near2 electrical) or microelectricalmechanical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or (micro near2 electrical) or (micro near2 mechanical) or (micro near2 electrical) or (micro near2 mechanical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) or (		222		LIODAT.	0004/00/00 40:00
or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical) and (fill adj2 factor)  133 ((mems or mem or microelectromechanical) or microelectricalmechanical or (micro near2 electro near2 mechanical) or (micro near2 electrical nor (micro near2 electrical or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) and (fill adj2 factor)) and (attenuat\$3 block\$3)  - 113 (((mems or mem or microelectrical or microelectrical or (micro near2 mechanical) or (micro near2 mechanical) or (micro near2 electrical) or (micro near2 mechanical) or (micro near2 electrical) or (micro near2 mechanical)) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3) actuat\$3) actuat\$3 actuat\$3 actuat\$3 actuat\$3 lock\$3) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3) same ((mirror\$1 micromechanical or microelectrical or microelectrical mechanical) or microelectrical or or microelectrical mechanical or (micro near2 electrical) or (micro near2 electrical) or (micro near2 mechanical)) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3 actuat\$3) same ((mirror\$1 micromechanical or (micro near2 mechanical)) or (micro near2 electrical near2 mechanical)) or (micro near2 electrical)	-	232			2004/09/03 10:33
microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical) and (fill adj2 factor)  133 ((mems or mem or microelectromechanical or microelectrical near2 mechanical) or (micro near2 electrical or microelectrical near2 mechanical) or (micro near2 electrical or microelectrical near2 mechanical) or (micro near2 electrical or microelectrical near2 mechanical) and (fill adj2 factor)) and (attenuat\$3 block\$3) ((mems or mem or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical or microelectricalmechanical or (micro near2 electrical or microelectricalmechanical or (micro near2 electrical or microelectrical near2 mechanical) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and (fill spivot\$3 rotat\$3 actuat\$3) same (mirros\$1) microelectrical or microelectrical near2 mechanical) or (micro near2 electrical or microelectrical near2 mechanical) or (micro near2 electrical or microelectricalmechanical or (micro near2 electrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical or microelectrical near2 mechanical) or (micro near2 electrical or microelectrical near2 mechanical) or (micro near2 electrical or microelectrical or microelectrical or microelectrical or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro n					
(micro near2 electrical near2 mechanical)) and (fill adj2 factor)  133 ((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) and (fill adj2 factor)) and (attenuat3 block\$3)  133 (((mems or mem or microelectromechanical) or microelectrical mechanical or (micro near2 electrical) or (micro near2 mechanical) or microelectrical or microelectrical mechanical or (micro near2 electrical) or (micro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectrical near2 mechanical)) and (fill adj2 factor)) and (attenuat3 block\$3)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)  1 38 (((mems or mem or microelectromechanical or microelectrical or microelectrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 e	!				
factor) ((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 electrical) and (fill adj2 factor)) and (attenuat\$3 block\$3)  - 113 (((mems or mem or microelectromechanical) or microelectrical or micromechanical) or (micro near2 electrical) or (micr					
133    ((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electrical) and (fill adj2 factor)) and (attenuat\$3 block\$3)   ((mems or mem or microelectromechanical or microelectricalmechanical or (micro near2 electro near2 mechanical) or (micro near2 electro near2 mechanical) or (micro near2 electrical) or (micro near2 electrical) or (micro near2 electron) and (attenuat\$3 block\$3)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)   ((mems or mem or microelectromechanical or microelectrical or microelectricalmechanical) or (micro near2 electronear2 mechanical) or (micro near2 electrical) or (micro near2 electrica			, `	I IDIVI_I DB	
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- 113   factor)) and (attenuat\$3 block\$3)   (((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectrical mechanical or (micro near2 electrical) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)   (((mems or mem or microelectrical or microelectrical near2 mechanical) or microelectrical or microelectrical or microelectrical or microelectrical or microelectrical or microelectrical near2 mechanical) or microelectrical or microelectrical near2 mechanical) or microelectrical or microelectrical near2 mechanical) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3) same ((mirror\$1 microelectrical or microelectrical near2 mechanical) or (micro near2 electrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical) or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3) same ((mirror\$1 microelectrical or microelectrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near2 electrical near2 mechanical) or (micro near2 electrical) or (micro near3 mechanical) or (micro near3 mechanical) or (micro near3 mechanical) or (micro near3 mechan					
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micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3 actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj	_	48		USPAT:	2004/09/01 18:55
or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3 actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj					
microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3 actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj				1	
factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3 actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj					
actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj				IBM_TDB	
mirror\$1)) reflect\$4))) and (multiplex\$3 wavelengths					
(wavelength near3 channels))				LICDAT	0004/00/04 40:40
- 14 (((((mems or mem or microelectromechanical or USPAT; 2004/09/01 18:42	Į <del>-</del>	14		1	ZUU4/U9/U1 18:42
micromechanical or (micro near2 electro near2 mechanical) US-PGPUB; or (micro near2 mechanical) or microelectrical or EPO; JPO;	[				
micro near2 mechanical) or micro near2 electrical or DERWENT;					
(micro near2 electrical near2 mechanical)) and (fill adj2 IBM_TDB	1				
factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3				.5	
actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj					
mirror\$1)) reflect\$4))) and (multiplex\$3 wavelengths					
(wavelength near3 channels))) and (high adj2 fill adj2 factor)					

-	1	(((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:58
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3		
		actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj		
		mirror\$1)) reflect\$4))) and (multiplex\$3 wavelengths		
		(wavelength near3 channels))) and cantilever		
ł <b>-</b>	2327	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:58
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and cantilever	IBM_TDB	
-	1230	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:59
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT:	
		(micro near2 electrical near2 mechanical)) and cantilever)	IBM TDB	
		and ((mirror\$1 micromirror\$1 (micro adj mirror\$1) reflect\$4))	1011-100	
	134	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:37
-	134	micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB:	2007/03/01 18.3/
			!	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and cantilever)	IBM_TDB	
		and ((mirror\$1 micromirror\$1 (micro adj mirror\$1) reflect\$4)))	1	
		and ((attenuat\$3 block) same (wavelength\$1 channel\$1		
	404	multiplex\$3))	LIODAT	0004/00/04 40 00
-	124	((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:00
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and cantilever)	IBM_TDB	
İ		and ((mirror\$1 micromirror\$1 (micro adj mirror\$1) reflect\$4)))		
		and ((attenuat\$3 block) same (wavelength\$1 channel\$1		
		multiplex\$3))) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)	:	
-	4226	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:37
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
1		(micro near2 electrical near2 mechanical)) and ((attenuat\$3	IBM_TDB	
		block) same (wavelength\$1 channel\$1 multiplex\$3))		
-	91	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:38
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and ((attenuat\$3	IBM_TDB	
		block) same (wavelength\$1 channel\$1 multiplex\$3))) and	-	
		(assymetric offset) near5 (pivot\$3 tilt\$3 rotat\$3 actuat\$3 axis		
		axes)		
_	91	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:38
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and ((attenuat\$3	IBM_TDB	
		block) same (wavelength\$1 channel\$1 multiplex\$3))) and		
		((assymetric\$2 offset) near5 (pivot\$3 tilt\$3 rotat\$3 actuat\$3		
	[	axis axes))	1	1
_	233	(mems or mem or microelectromechanical or	USPAT;	2004/09/03 10:33
1	233	micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	2004/00/00 10:00
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		1,	םם ו_וייטו	
L	L	factor)	L	L

-	135	((mems or mem or microelectromechanical or	USPAT;	2004/09/03 10:34
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor) ) and (multiplex\$4 wavelengths channels)		
-	66	(((mems or mem or microelectromechanical or	USPAT;	2004/09/03 10:35
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor) ) and (multiplex\$4 wavelengths channels)) and		
	4	(attenat\$3 block\$3)	LICDAT.	0004/00/02 40:40
-	1	((((mems or mem or microelectromechanical or	USPAT;	2004/09/03 10:42
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2	DERWENT;	į
		factor)   and (multiplex\$4 wavelengths channels)) and	IBM_TDB	
		(attenat\$3 block\$3)) and (electrode with potential with mirror)		
_	0	(mirror with (landing) with electrode with potential) and	USPAT;	2004/09/03 10:43
_		attenuat\$3	US-PGPUB:	2007/03/03 10.43
		- attorisativo	EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	20	mirror with (landing) with electrode with potential	USPAT;	2004/09/03 10:47
	20	Time with (landing) with electrode with potential	US-PGPUB;	2004/05/00 10.4/
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	4	(mirror with (landing) with electrode with potential) and	USPAT:	2004/09/03 10:45
	İ	multiplex\$3	US-PGPUB;	200
			EPO; JPO;	
			DERWENT;	
İ			IBM_TDB	
-	41	mirror with electrode with ("same" near3 potential)	USPAT;	2004/09/03 10:47
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	5	(mirror with electrode with ("same" near3 potential)) and	USPAT;	2004/09/03 10:48
		attenuat\$3	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
	_	//mainung with all attends with (II = === II = === 0 == t == t == t == t	IBM_TDB	0004/00/00 10 50
-	5	((mirror with electrode with ("same" near3 potential)) and	USPAT;	2004/09/03 10:56
		attenuat\$3) not ((mirror with (landing) with electrode with	US-PGPUB;	
		potential) and multiplex\$3)	EPO; JPO; DERWENT;	
	[		IBM TDB	
	34969	mem or mems	USPAT;	2004/09/03 10:56
	04303	mont of monto	US-PGPUB;	2004/03/00 10:00
	<b>[</b>		EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	1746	(mem or mems ) and (circuit near5 substrate)	USPAT;	2004/09/03 10:57
			US-PGPUB;	= 30
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	24	(mem or mems ) and (fabricate near3 circuit near5 substrate)	USPAT;	2004/09/03 10:58
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
	<u></u>		IBM_TDB	
			···	

-	0	((mem or mems ) and (fabricate near3 circuit near5	USPAT;	2004/09/03 10:58
		substrate)) and attenuat\$3	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	3	((mem or mems ) and (fabricate near3 circuit near5	USPAT:	2004/09/03 11:08
		substrate)) and multiplex	US-PGPUB:	200 1100100 11100
		Substituto)/ and maniplex	EPO; JPO;	
			DERWENT;	
	27264	way along the mage 2 may display #2	IBM_TDB	0004/00/00 44.00
-	27364	wavelength near3 multiplex\$3	USPAT;	2004/09/03 11:08
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	963	(wavelength near3 multiplex\$3) and ((mirror micromirror	USPAT;	2004/09/03 11:10
		(micro near2 mirror\$1)) with (tilt\$3 rotat\$3 pivot\$3))	US-PGPUB;	
	•		EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	l 0	((wavelength near3 multiplex\$3) and ((mirror micromirror	USPAT;	2004/09/03 11:10
		(micro near2 mirror\$1)) with (tilt\$3 rotat\$3 pivot\$3))) and	US-PGPUB;	200 1700700 11.10
		((rotat\$3 tilt\$3 pivot\$3) with (center near4 gravity))	EPO; JPO;	
		((Total 40 thi 40 proof 40) with (center hear 4 gravity))	DERWENT:	
			,	
	45	(	IBM_TDB	0004/00/00 44:40
-	15	(wavelength near3 multiplex\$3) and ((off near3 center) with	USPAT;	2004/09/03 11:10
		(tilt\$3 rotat\$3 pivot\$3))	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	1	(US-20020135864-\$).did.	US-PGPUB	2004/09/03 11:14
-	8	(US-6760144-\$ or US-6778728-\$ or US-5965886-\$ or	USPAT;	2004/09/03 14:09
		US-6263123-\$).did. or (US-20030112507-\$ or	US-PGPUB	
1		US-20030223679-\$ or US-20040125361-\$ or		
		US-20020135864-\$).did.		
-	1	((US-6760144-\$ or US-6778728-\$ or US-5965886-\$ or	USPAT;	2004/09/03 11:16
	1	US-6263123-\$).did. or (US-20030112507-\$ or	US-PGPUB	
		US-20030223679-\$ or US-20040125361-\$ or		
		US-20020135864-\$).did.) and (polish\$3 near4 mirror)		
_	1	((US-6760144-\$ or US-6778728-\$ or US-5965886-\$ or	USPAT;	2004/09/03 11:16
	'	US-6263123-\$).did. or (US-20030112507-\$ or	US-PGPUB	
		US-20030223679-\$ or US-20040125361-\$ or	30-1 31 00	
	1	US-20020135864-\$).did.) and (polish\$3 near4 mirror)		
İ	4600		LICDAT.	2004/00/02 44:40
-	4693	((359/214,224,291,290,295,298) (385/15,18) (310/309)).ccls.	USPAT;	2004/09/03 14:10
		(//050/044 004 004 000 005 000) (005/45 40)	US-PGPUB	0004/00/00 44 45
-	1155	(((359/214,224,291,290,295,298) (385/15,18)	USPAT;	2004/09/03 14:10
	1	(310/309)).ccls.) and mem\$1	US-PGPUB	
-	1	(((((359/214,224,291,290,295,298) (385/15,18)	USPAT;	2004/09/03 14:10
	1	(310/309)).ccls.) and mem\$1) and wavlength\$1	US-PGPUB	
-	710	((((359/214,224,291,290,295,298) (385/15,18)	USPAT;	2004/09/03 14:10
	1	(310/309)).ccls.) and mem\$1) and wavelength\$1	US-PGPUB	
-	386	(((((359/214,224,291,290,295,298) (385/15,18)	USPAT;	2004/09/03 14:11
		(310/309)).ccls.) and mem\$1) and wavelength\$1) and	US-PGPUB	
	1	((mirror\$1 micromirror\$1) with (tilt\$3 rotat\$3 pivot\$3))		
L	1	[ [ [ [ ] ] ] ] ] [ [ ] [ ] [ ] [ ] [ ]	1	1